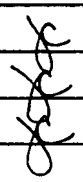



AP20 Rec'd PCT/PTO 09 JUN 2006

Sheet 1 of 1

Form PTO-1449 (REV. 1/06) US Dept. of Commerce PATENT & TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)	ATTY DOCKET NO. 128180	APPLICATION NO. 10/582344 PCT/FR2004/003203
	APPLICANT Elisabeth DELEVOYE	
	FILING DATE June 9, 2006	2856

U.S. PATENT DOCUMENTS				
Examiner Initials	Cite No.	Document Number	Date	Name

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	1.	EP 0 904 522 A	03/31/1999	EUROPE		
	2.	WO 02/057728 A	07/25/2002	WIPO		
	3.	EP 1 126 242 A	08/22/2001	EUROPE		

OTHER DOCUMENTS		
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)
	4.	MAENAKA et al.; "A study of silicon angular rate sensors using anisotropic etching technology"; <i>Sensors and Actuators</i> ; Vol. A43; No. 1/3; May 1, 1994; pgs. 72-77.

EXAMINER John Chapman	DATE CONSIDERED 10/3/07
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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Date: June 9, 2006